Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Previously presented) A micro electromechanical systems (MEMS) device comprising:

a scanning probe microscopy (SPM) component;

one or more fluidic channels formed in the SPM component;

one or more control valves to control a flow of fluid in the one or more fluidic channels; and

one or more movable members formed in the SPM component, at least one fluidic channel being formed in each movable member, wherein fluid flow through the at least one fluidic channel produces movement in the movable member.

2. (Currently amended) A method for nanomachining using ~~the~~ a MEMS device, the MEMs device comprising: ~~of claim 1.~~

a scanning probe microscopy (SPM) component;

one or more fluidic channels formed in the SPM component;

one or more control valves to control a flow of fluid in the one or more fluidic channels; and

one or more movable members formed in the SPM component, at least one fluidic channel being formed in each movable member, wherein fluid flow through the at least one fluidic channel produces movement in the movable member.

3. (Previously presented) A micro electromechanical systems (MEMS) device comprising:

a scanning probe microscopy (SPM) component;

at least one fluidic channel formed in the SPM component; and

a venturi tube formed along a portion of the fluidic channel,

wherein a vacuum can be developed by a flow of a gas or fluid through the venturi tube.

4. (Currently amended) A micro electromechanical systems (MEMS) device comprising:

a scanning probe microscopy (SPM) component;

one or more movable members formed in the SPM component;

a fluidic channel formed in a first movable member, the fluidic channel configured to deliver fluid to a tip of the SPM component;

one or more control valves formed in the SPM component to control a flow of fluid in the fluidic channel; and

an amount of an isotope disposed along the fluidic channel,

wherein ~~the~~ particles emitted by the isotope can be delivered by a fluid flowing in the fluidic channel to the tip to affect ~~the~~ charge distribution in a region about the tip.

5. (Currently amended) A method for performing nanomachining on a workpiece using ~~the~~ a MEMs device, the MEMs device comprising:

a scanning probe microscopy (SPM) component;

one or more movable members formed in the SPM component;

a fluidic channel formed in a first movable member, the fluidic channel configured to deliver fluid to a tip of the SPM component;

one or more control valves formed in the SPM component to control a flow of fluid in the fluidic channel; and

an amount of an isotope disposed along the fluidic channel,

wherein particles emitted by the isotope can be delivered by a fluid flowing in the fluidic channel to the tip to affect charge distribution in a region about the tip, ~~of claim 4~~ wherein the particles are delivered to the tip.

6 - 7. (Canceled)

8. (Previously presented) The MEMS device as recited in claim 4 wherein the isotope is Americium 241.

9. (Original) The MEMS device as recited in claim 4 wherein the amount of isotope is disposed in a single isotopic region on the SPM device, wherein the single isotopic region contains 1 microcurie or less of radioactivity.

10 - 25. (Canceled)

26. (Currently amended) A method of performing a nanomachining operation comprising manipulating a device ~~as recited in claim 4~~ relative to a surface, including constraining motion of the device in a specific or constrained region,

the device comprising:

a scanning probe microscopy (SPM) component;

one or more movable members formed in the SPM component;

a fluidic channel formed in a first movable member, the fluidic channel configured to deliver fluid to a tip of the SPM component;

one or more control valves formed in the SPM component to control a flow of fluid in the fluidic channel; and

an amount of an isotope disposed along the fluidic channel,

wherein particles emitted by the isotope can be delivered by a fluid flowing in the fluidic channel to the tip to affect charge distribution in a region about the tip.

27. (Previously presented) A method as in 26 in which the nanomachining operation uses chemical or biological chips or devices in which material therefore is placed in wells in a regular arrangement on a plane or surface(s).

28. (Previously presented) A method as in 27 in which the material is DNA which has been marked optically, electrically or chemically so as to interact with optical, electrical or chemical detectors or emitters associated with or integrated in the device.

29. - 37. (Canceled)

38. ((Previously presented)) The MEMS device of claim 1 further comprising a cantilever formed in the SPM component and operatively coupled to the moveable members, wherein movement in the movable members serves to move the cantilever.

39 - 40. (Canceled)

41. (Previously presented) The MEMS device of claim 4 wherein the fluid flow comprises one of moving fluid from the fluidic channel formed in the first moveable member to create at least a partial vacuum thereby effecting movement of the first moveable member and moving fluid into the fluidic channel formed in the first moveable member wherein a force of the fluid effects movement of the first moveable member.

42. (Previously presented) The MEMS device of claim 4 wherein fluid flow through the at least one fluidic channel produces movement in the first movable member.

43. (Previously presented) The MEMS device of claim 42 further comprising a cantilever formed in the SPM component and operatively coupled to the moveable members, wherein a fluidic channel is formed in each moveable member, wherein movement in the movable members serves to move the cantilever.

44. (Previously presented) The MEMS device as recited in claim 4 wherein the moveable members act as passive elements.

45. (Previously presented) The MEMS device as recited in claim 4 wherein the moveable members produce electrical signals during movement, wherein the electrical signals serve to control subsequent movements.

46. (Previously presented) The MEMS device as recited in claim 45 wherein the electrical signals serve to obtain one of a predetermined motion of a first moveable member, a predetermined displacement of the first moveable member, a zero displacement position of the first moveable member.

47. (Previously presented) The MEMS device as recited in claim 4 further comprising a circuit for monitoring changes in charge accumulation in the fluidic channel as the isotope is moved by fluid flow.

48. (Currently amended) A method for nanoelectric discharge machining using ~~the~~ a MEMS device ~~as recited in claim 4~~, the method comprising imaging a surface to be machined and measuring surface features of the surface to be machined, the imaging and measuring being performed using a scanning probe microscopy technique

the MEMs device comprising:

a scanning probe microscopy (SPM) component;

one or more movable members formed in the SPM component;

a fluidic channel formed in a first movable member, the fluidic channel configured to deliver fluid to a tip of the SPM component;

one or more control valves formed in the SPM component to control a flow of fluid in the fluidic channel; and

an amount of an isotope disposed along the fluidic channel,

wherein particles emitted by the isotope can be delivered by a fluid flowing in the fluidic channel to the tip to affect charge distribution in a region about the tip.

49 - 58. (Canceled)

59. (Previously presented) A micro electromechanical systems (MEMS) device comprising:

a scanning probe microscopy (SPM) component;

a fluidic channel formed in the SPM component, the fluidic channel configured to deliver fluid to a tip of the SPM component;

an amount of an isotope disposed along the fluidic channel, wherein the particles emitted by the isotope can be delivered by a fluid flowing in the fluidic channel to the tip to affect the charge distribution in a region about the tip; and

a circuit for monitoring changes in charge accumulation in the fluidic channel as the isotope is moved by a flow of fluid.